

Fabrication and characterisation of 3D diamond detectors

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- ▶ Introduction to 3D diamond detectors
 - ▶ Why diamond?
 - ▶ Why 3D?
- ▶ Fabrication of graphitic electrodes
 - ▶ Improvement to this technique
- ▶ Characterisation of detectors using both fabrication techniques
 - ▶ Resistivity measurements - electrical properties
 - ▶ Raman spectroscopy measurements - material content
 - ▶ Cross polarised images - stress measurements

Introduction to 3D diamond detectors

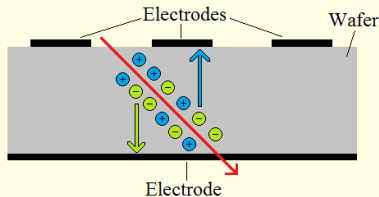
When compared to silicon, diamond has:

- ▶ Higher displacement energy
 - ▶ More radiation tolerant
- ▶ Higher thermal conductivity
 - ▶ Less cooling required
- ▶ Larger band gap
 - ▶ Lower leakage current

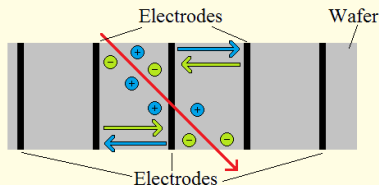
- ▶ Trapping
 - ▶ Loss of charge
- ▶ Larger band gap
 - ▶ Fewer electron-hole pairs produced
- ▶ Higher cost

Radiation tolerance is key for tracking detectors in the HL-LHC

Planar



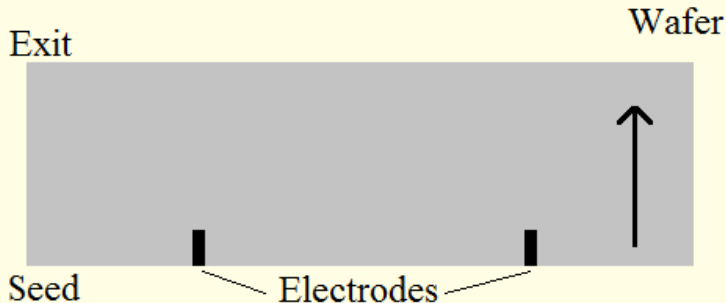
3D



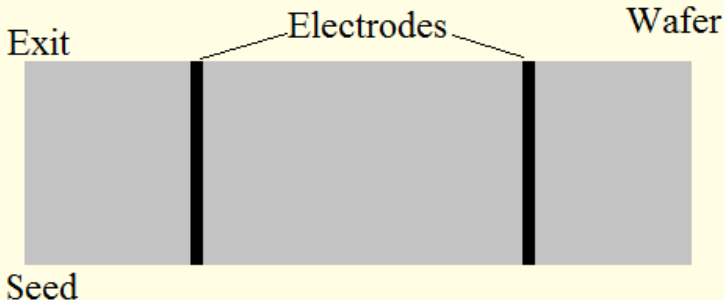
- ▶ Planar detectors have electrodes on both sides of wafer
- ▶ 3D detectors have electrodes through the wafer bulk
- ▶ Shorter charge collection distance in 3D geometry
 - ▶ Lower trapping probability
 - ▶ Higher detection efficiency
- ▶ Higher electric field in 3D

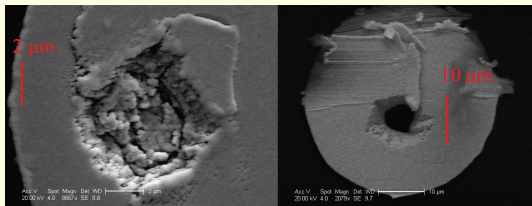
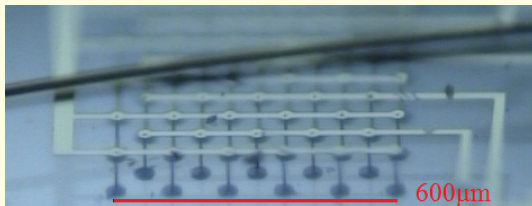
Electrode fabrication technique

- ▶ Use a Ti:Sapphire 100 fs pulse length laser
- ▶ Phase transition from diamond to graphite occurs at focal point
- ▶ Moving diamond wafer relative to focal point forms continuous electrode



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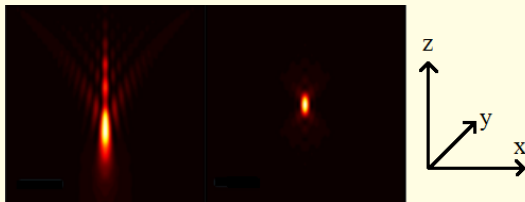




- ▶ Pulp formed on seed side
- ▶ Crater formed on exit side due to lower density of electrode material

- ▶ Current fabrication technique limits electrode diameter to $6\ \mu\text{m}$.
 - ▶ Limits active area of detector
- ▶ Resistivity limited to $2\ \Omega\text{cm}$
 - ▶ Highly conductive channels desirable (resistivity $\ll 1\ \Omega\text{cm}$)
- ▶ Both effects are due to aberrations and distortions of the laser pulses
 - ▶ Distortion by refraction at the diamond surface
 - ▶ Depth-dependent aberrations within the diamond
- ▶ These are rectified using a dynamic adaptive wavefront

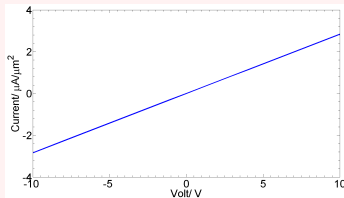
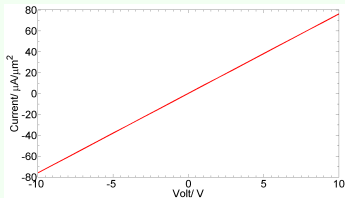
- ▶ Use a spatial light modulator (SLM) to alter focal spot^[1]
- ▶ A phase pattern is calculated to adjust for the aberrations at a particular depth
- ▶ The patterns are calculated every 10 μm
- ▶ Results in a smaller focal spot (1 μm , right)



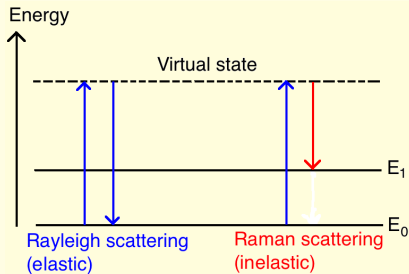
[1]. B. Sun, P. Salter, M. Booth, doi:10.1063/1.4902998

Characterisation of 3D diamond detectors

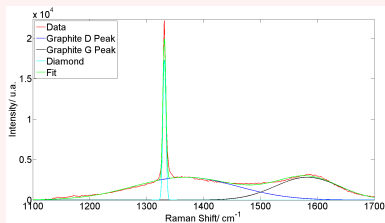
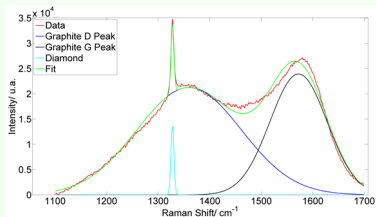
- ▶ Graphitic electrodes fabricated with and without an SLM
- ▶ Electrical properties measured from current-voltage curves
- ▶ Both techniques produce ohmic electrodes
- ▶ Lower resistance observed when using an adaptive wavefront (left, green) than without (right, red).
- ▶ Resistivities of $0.2 \Omega\text{cm}$ and $2 \Omega\text{cm}$ with and without an adaptive wavefront, respectively
 - ▶ Much closer to ideal electrodes



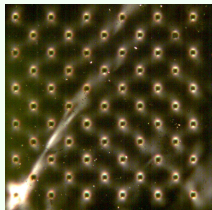
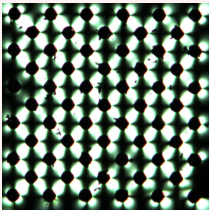
- ▶ Photons from a laser are incident on the surface of a sample
- ▶ Photons are scattered by molecules within the sample
 - ▶ Results in energy loss from vibrational levels
- ▶ Spectrometer analyses energy of scattered photons
 - ▶ Spectrum is characteristic of the molecule
- ▶ Helps to probe the material content of fabricated electrodes



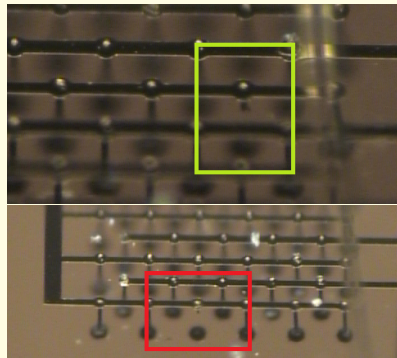
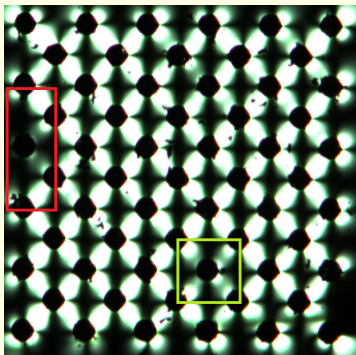
- ▶ Three peaks: One narrow diamond peak (1330 cm^{-1}) and two broad graphite peaks (1350 cm^{-1} and 1583 cm^{-1} for graphite D and G peaks, respectively)
- ▶ Apply fits to extract heights of diamond and graphite G peaks
 - ▶ Ratio gives an estimate of graphite content inside electrode
- ▶ Lower ratio observed when using an adaptive wavefront (left, 0.2–0.4) than without (right, 2–4)



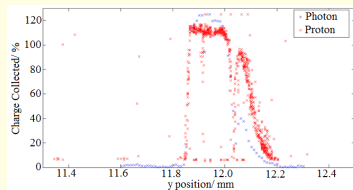
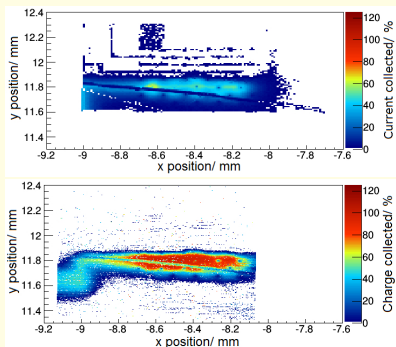
- ▶ Level of stress within diamond observed using two crossed polarisers at 90°
 - ▶ Bright areas indicate high stress
- ▶ Dominant source of stress without using an adaptive wavefront (left) is from electrodes on diamond bulk.
- ▶ Dominant source of stress using an adaptive wavefront (right) is the wafer purity
- ▶ Can reduce the electrode separation when using an SLM
 - ▶ More cells within detector, so better particle tracking



- ▶ Technique can also be used to determine electrode yield
- ▶ Partially formed electrodes have lower surrounding stress
- ▶ Electrode yield higher when using an adaptive wavefront (100%) than without (90%)



- ▶ Photon (left, top) and proton (left, bottom) data taken for a detector produced without an adaptive wavefront^[2]
- ▶ Full charge collection observed, and no significant charge sharing seen
- ▶ Proton data compared to simulations, with reasonable agreement (see talk by G. Forcolin)



[2] G.T. Forcolin, V. Grilj, B. Hamilton, L. Li, M. McGowan, S.A. Murphy, A. Oh, N. Skukan, D. Whitehead, A. Zadoroshnyj, doi:10.1016/j.diamond.2016.02.005

- ▶ Graphitic electrodes have been fabricated with and without an adaptive wavefront
- ▶ Comparing the techniques shows a reduction in the resistivity and induced stress in the diamond when using an SLM, while increasing the graphitic content
- ▶ A detector will be fabricated using an SLM, and the performance will be investigated with particle beams
- ▶ The results will be compared to a detector fabricated without an SLM^[2]

- ▶ G. Forcolin (see next talk), A. Oh [1]
- ▶ M. Booth, P. Salter, B. Sun [2]
- ▶ L. Li, D. Whitehead [3]
- ▶ A. Zadoroshnyj [4]
- ▶ V. Grilj, N. Skukan [5]
- ▶ Diamond Light Source, Oxford
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